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Sheet 1 of 1 10-18-01

| Form PTO-1449 | | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | | ATTY. DOCKET NO. M122-1725 | SERIAL NO. Filed Herewith | |
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| U.S. PATENT DOCUMENTS | | | | | | |
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| | AP | | | | | |
| | AQ | | | | | |
| OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | |
| DA | AR | Hiratani, M. et al., "A Conformal Ruthenium Electrode for MIM Capacitors in Gbit DRAMs Using the CVD Technology Based on Oxygen-Controlled Surface Reaction, IEEE, 2000 Symposium on VLSI Technology Digest of Technical Papers, pp. 102-103. | | | | |
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| DA | AS | Kim, Y. et al., "Growth of RuOx Thin Films by Metal Organic Chemical Vapor Deposition", IEEE 1999, pp. 501-502. | | | | |
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| EXAMINER | | | DATE CONSIDERED 5-08-02 | | | |
| *EXAMINER: Initial reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | | | | | | |

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